



# Xper-WLI

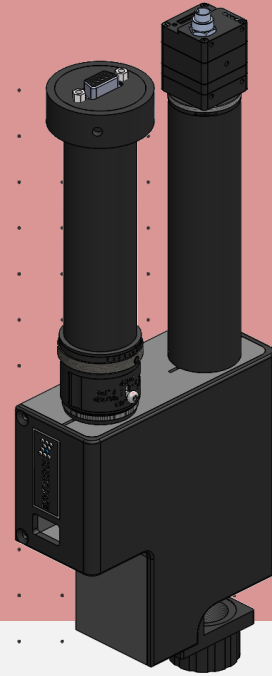
## (White Light Interferometric Profiler) by NANOBASE

Thickness and profile detection in nanoscale

WLI & PSI mode change function

Industrial application : sample defect / structure / quality verification

Sample types : Nanomaterials, Biomaterials, Chemical structures



### Specifications

#### Measurement Principle

White light phase shift interferometry

#### Measuring Performance

Three-dimensional surface profile measurements, surface roughness measurements

#### Z-axis Resolution

1.75 nm (surface measurements noise level)

#### CCD Resolution

2464 x 2056 pixels

#### High Stiffness Scanner Range (Piezo)

30µm

#### Objective Lens Options

10x, 20x, 50x, 100x

#### Illuminator

LED lamp

#### Filter Module for PSI

532nm, 633nm (Visible range : 400~ 750nm)

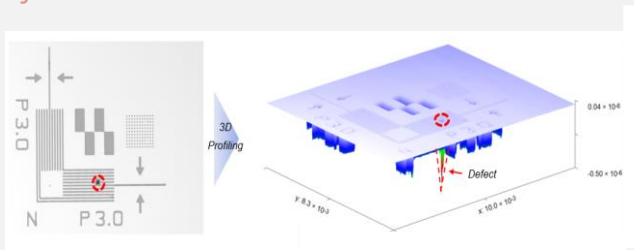
#### PC

- CPU : Octa Core 3.0 GHz
- RAM : 16 GB
- Storage : SSD 128 GB
- OS : Windows 10

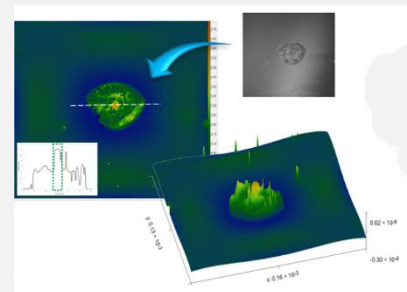
#### Software

- Auto experiment condition set
- Post processing : Smoothing / z-axis control factor / offset control
- X/Y axis profile extraction

### Analysis Data



Semiconductor device defect analysis



Oral cell analysis